

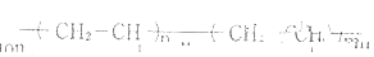
明

福
福
行

富
田
一

三

アクリル系重合体



CH₃

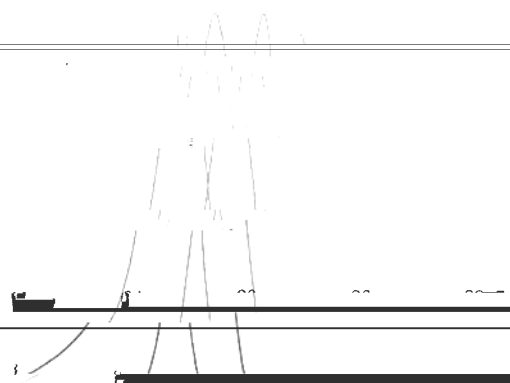
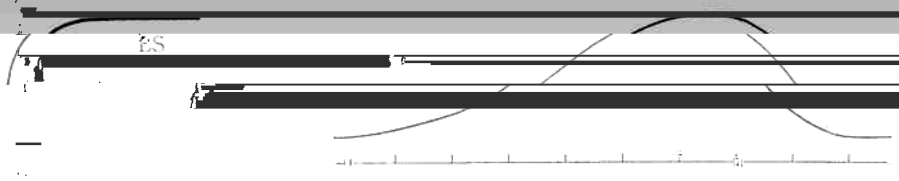
CMS

CH₃

CH₃

CH₂-CH₂

CH₃ CH₃



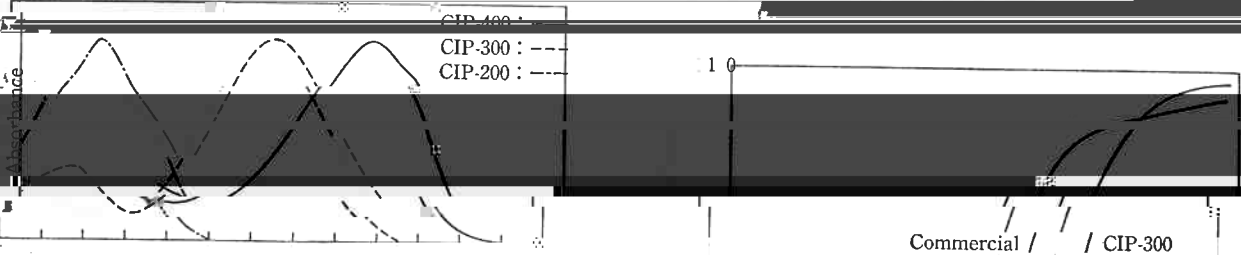
Count

LS: light scattering

RI: differential refractometer

by a conventional method [unreadable]

1985 1990



CIP-200 :

Dose (mI/cm²)

2.24

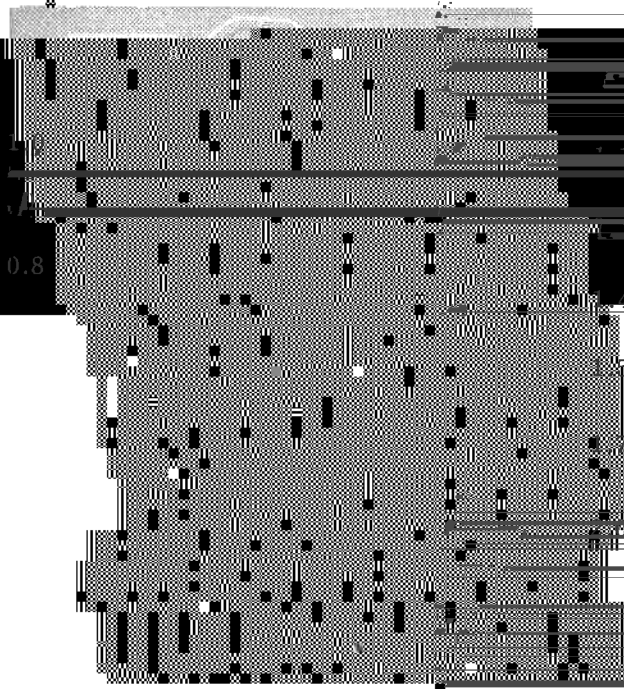
2.83

3.17

3.56

Photo 1 Radial pattern of CTD 900 (a) and

Film thickness: 1.0mm



0.8

0.9

るから、基本的に現状のレジストプログラマも面する

1 2 3 4 5 6

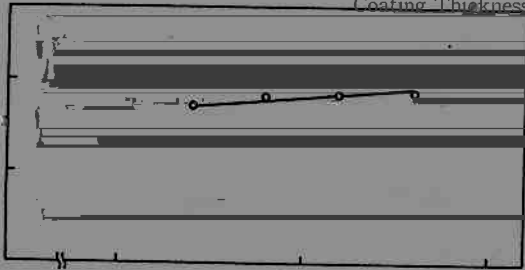
Spitz Speed (X30)

Normalized thickness

PERMANENT

Contact

Coating Thickness : 1.5μm



face width

width to

Ratio of

1.0

0.5

○ Air

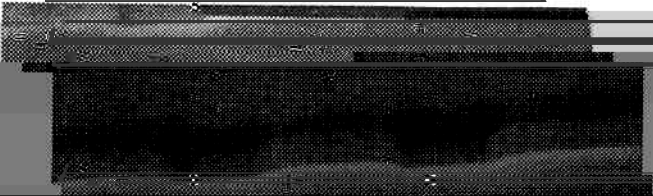
Commercial

0.5

1.0

1.5

L. I.

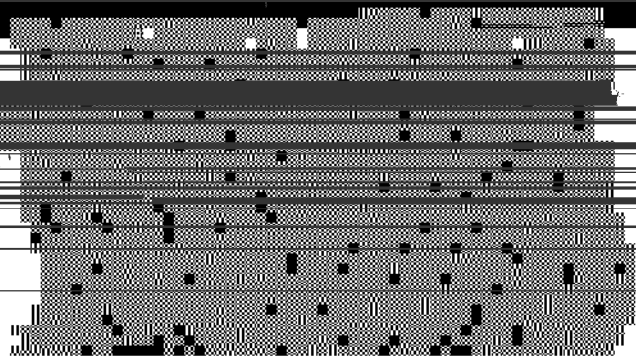


であり、通常のウェットエッチングの手法を採用する

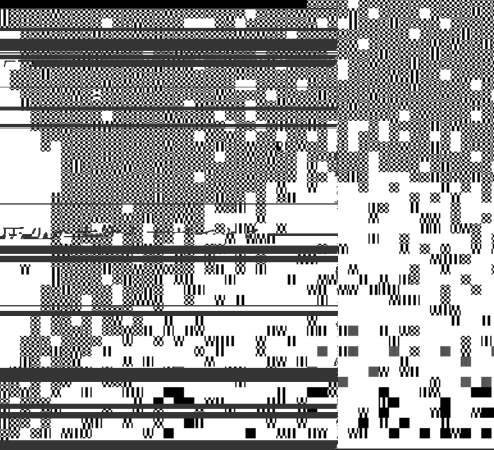
とができる。

(7) 剥離

剥離は、



と、



[Redacted text block]

(1974)

(1982)

[Redacted text block]

[Redacted text block]